

<b>INFORMATION DISCLOSURE CITATION</b> <small>(Use several sheets if necessary)</small>				ATTY DOCKET NO. <b>TROLOGY 02.02</b>	APPLICATION NO. <b>10/536,576</b>	
				APPLICANT(S) <b>Szwajkowski et al.</b>		
				FILING DATE <b>February 6, 2006</b>	GROUP ART UNIT	
				<b>U.S. PATENT DOCUMENTS</b>		
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
/HL/	4,583,855	04.22.1986	Bareket	356	351	
/HL/	6,304,330	10.16.2001	Millerd et al.	356	521	
/HL/	6,552,808	04.22.2003	Millerd et al.	356	521	
/HL/	3,950,103	04.13.1976	Schmidt			
/HL/	6,128,080	10/2000	Janik et al.			
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/HL/	2003/0095264	05/2003	Ruchet	356	491	
<b>FOREIGN PATENT DOCUMENTS</b>						
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						YES
						NO
/HL/	DE 196 52 113	18.06.1998	Germany			
/HL/	WO 2004/051182	17.06.2004	PCT	G01B	9/02	
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>						
/HL/		Hettwer, et al., "Three Channel Phase-Shifting Interferometer Using Polarization-Optics and a Diffraction Grating", The International Society for Optical Engineering, Optical Engineering, Vol. 39, pps. 960-966, April 2000 (abstract only).				
/HL/		Nakadate et al., "Real-Time Fringe Patter Processing and its Applications", Proc. of SPIE, Vol. 2544, pps. 74-86, June 1995 (abstract only).				
EXAMINER /Hwa Lee/			DATE CONSIDERED 12/22/2007			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>						

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			<b>Szwaykowski et al.</b> <b>FILING</b> <b>February 6, 2006</b> <b>GROUP ART</b>				
<b>U.S. PATENT DOCUMENTS</b>							
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES      NO
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/HL/		Sivakumar, et al., "Large Surface Profile Measurement with Instantaneous Phase-Shifting Interferometry", Optical Engineering, February 2003, Vol. 42, Issue 2, pps. 367-372 (abstract only).					
/HL/		Koliopoulos, Chris L., "Simultaneous Phase-Shift Interferometer", Proceedings of SPIE, Vol. 1531, Advanced Optical Manufacturing and Testing II, 1992, pps. 119-127.					
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